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ELECTRONIC INFORMATION DISCLOSURE STATEMENT

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Title of Invention**A METHOD AND SYSTEM FOR INTELLIGENT AUTOMATED RETICLE
MANAGEMENT**

Application Number:

Confirmation Number:

First Named Applicant: Richard Burda

Attorney Docket Number: BUR920040031US1

Search string: (6640151 or 5841660 or 4796194 or 6564113 or 6615098 or 20020156548).pn.

US Patent Documents**Note: Applicant is not required to submit a paper copy of cited US Patent Documents**

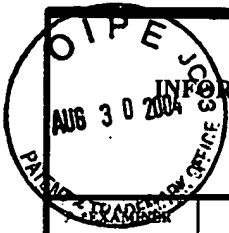
| Init | Cite.No. | Patent No. | Date | Patentee | Kind | Class | Subclass |
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| SRG | 1 | 6640151 | 2003-10-28 | Somekh, et al | | | |
| SRG | 2 | 5841660 | 1998-11-24 | Robinson, et al | | | |
| SRG | 3 | 4796194 | 1989-01-03 | Atherton | | | |
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| Init | Cite.No. | Pub. No. | Date | Applicant | Kind | Class | Subclass |
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| SRG | 1 | 20020156548 | 2002-10-24 | Arackaparambil, et al | | | |

Signature

| Examiner Name | Date |
|------------------|------------|
| /Steven Garland/ | 08/15/2006 |



INFORMATION DISCLOSURE CITATION
(Use several sheets if necessary)

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| Docket Number (Optional) BUR920040031US1 | Application Number 10/711079 |
| Applicant(s) Burda, et al. | |
| Filing Date 08/20/04 | Group Art Unit Unknown |

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| INITIAL | | |
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| EXAMINER /Steven Garland/ | DATE CONSIDERED 08/15/2006 |
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